

IN SITU INFRARED STUDY OF CATALYTIC DECOMPOSITION OF NO

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In Situ Infrared Study of Catalytic Decomposition of NO

ABSTRACT

During the first semi-annual period of the project, NO adsorption, CO adsorption, NO temperature-programmed desorption and decomposition (TPD), and temperature-programmed reaction (TPR) of NO-CO have been studied over 0.5 wt% Rh/SiO₂ catalysts by a combined infrared and mass spectrometric technique. Infrared study reveals that the high wavenumber Rh-NO δ^- at 1723-1740 cm⁻¹ is the dominant adsorbate during TPD and TPR with NO:CO = 1:1. During TPR, CO reduces part of Rh surface resulting in the formation of the low wavenumber Rh-NO δ^- at 1634-1680 cm⁻¹. Increasing CO partial pressure (i) promotes the formation of Rh to Rh⁰ sites, producing linear CO, (ii) increases the selectivity to N₂O below the light-off temperature, (iii) raises the light-off temperature, and (iv) promotes the formation of Si-NCO and Rh-NCO. Comparison of results of the present study with those of previous studies on 4 wt% Rh/SiO₂ shows that different dispersion of Rh crystallites on SiO₂ support results in significant variation in chemisorptive and reactive properties of Rh metal for NO-CO reaction.

INTRODUCTION

In situ infrared (IR) spectroscopy has been widely used to study adsorbates on supported metal catalysts [1-7]. Infrared spectroscopy provides unique information on both properties of adsorbates and characteristics (i.e. oxidation state and geometric structure) of the surface sites that chemisorb adsorbates. Depending on the specific reaction conditions, adsorbates may follow various pathways: (i) desorbing to the gas phase and returning to its initial reactant form, (ii) surface reactions leading to the formation of both desired and side products, and (iii) residing on the surface and remaining inactive. Identification of the fate of an adsorbate requires simultaneous measurements of variation in concentration of adsorbates as well as that of gaseous reactants and products under transient conditions [1,7,8]. One effective approach for such measurements is a combined IR and mass spectrometric (MS) technique in which *in situ* IR spectroscopy measures

the concentration of adsorbates and MS determines the concentration of the gaseous species resulting from interactions and reactions of the adsorbates.

Both IR and MS have been widely used in catalysis research. These techniques have often been used separately, resulting in the difficulty in correlating IR with MS results. Few studies using the combined IR and MS technique have been reported. An earlier combined IR-MS study of NO and CO adsorption on a 4 wt% Rh/SiO₂ catalyst with Rh crystallite size of 63 Å revealed that exposure of linear and gem-dicarbonyl CO to gaseous NO leads to desorption of both forms of adsorbed CO and adsorption of NO as Rh-NO^{δ-} and Rh-NO^{δ+} in the 298-413 K temperature range [9]. Transient IR-MS study also showed that adsorbed NO^{δ-} on the surface of Rh crystallite is an active precursor for NO dissociation [10]. Due to the significant difference in Rh loading and dispersion between 4 wt% Rh/SiO₂ and a three-way Pt-Rh automobile catalyst, results obtained from 4 wt% Rh/SiO₂ may not be directly relevant to the behavior of adsorbates on the surface of the three-way catalyst.

The objective of this study is to determine the reaction pathways of adsorbed NO during temperature-programmed desorption, decomposition, and reaction with CO on 0.5 wt% Rh/SiO₂. 0.5 wt% Rh/SiO₂ contains highly dispersed Rh crystallite of which dispersion resembles that of Rh on the typical three-way catalyst. Results of this study are compared with those of 4 wt% Rh/SiO₂ [8-10] and other results described in the literature to shed light on the behavior of adsorbed NO on the highly dispersed Rh catalysts under reaction conditions.

EXPERIMENTAL

The catalyst used in this study was a 0.5 wt% Rh/SiO₂ which was prepared by incipient wetness impregnation of large pore (Stream, 300 m² g⁻¹) SiO₂ support with RhCl₃·3H₂O (Alfa Chemicals) solution. The ratio of the volume of solution to the weight of support material used for the catalyst was 1 cm³ to 1 g. After impregnation, the catalyst sample was dried overnight in air at 303 K and reduced in flowing H₂ at 673 K for 16 h. The catalyst was pressed into a thin disk and placed in an *in situ* infrared (IR) reactor cell capable of operating up to 873 K and 6 MPa. The

details of the *in situ* infrared (IR) reactor cell, experimental apparatus, and procedures have been reported elsewhere [8]. The catalyst in the IR cell was further reduced with H₂ at 673 K for 2 h prior to initiating the reaction study. The reaction mixture consisted of CO (Commercial grade), NO (UHP), and He (UHP) which were controlled by mass flow controllers.

Temperature-programmed desorption (TPD) of adsorbed NO was carried out at a heating rate of 15 K min⁻¹ in flowing helium at 30 cm³ min⁻¹; temperature-programmed reaction of NO-CO was studied at a heating rate of 15 K min⁻¹ with mixture of NO:CO:He = 10:10:30 cm³ min⁻¹ and NO:CO:He = 5:50:30 cm³ min⁻¹. The change in concentration of adsorbates was monitored by an FT-IR spectrometer with a resolution of 4 cm⁻¹; the effluent from the IR reactor cell was monitored continuously using a Balzers QMG 112 quadrupole mass spectrometer (MS). The mass-to-charge (*m/e*) ratios monitored were 28 for CO and N₂, 30 for NO, and 44 for both N₂O and CO₂.

RESULTS AND DISCUSSION

Figure 1 shows the infrared spectra of adsorbed NO at 303 K and 0.1 MPa during temperature-programmed desorption and decomposition. Exposure of Rh/SiO₂ catalyst to 0.1 MPa of NO at 303 K in a batch mode produced gaseous N₂O bands at 2236 and 2212 cm⁻¹, weakly adsorbed NO on SiO₂ at 1857 and 1605 cm⁻¹, and adsorbed NO on Rh at 1723 cm⁻¹. The 1723 cm⁻¹ band may be assigned to a high wavenumber Rh-NO^{δ-} which will be further discussed. Prolonged exposure of the catalyst to gaseous NO led to the growth of the band at 1723 cm⁻¹ and decrease in the IR intensity of weakly adsorbed NO on SiO₂. Gaseous N₂O and weakly adsorbed NO were removed by flowing helium while the Rh-NO^{δ-} band continued to increase in intensity.

Figure 1 also shows that temperature-programmed desorption of adsorbed NO caused a decrease in the Rh-NO^{δ-} intensity and an upward shift from 1723 cm⁻¹ at 303 K to 1740 cm⁻¹ at 483 K. Closer examination reveals that the bands in 1723-1740 cm⁻¹ region consist of at least two bands. These bands are centered about 1740 cm⁻¹ at temperatures above 423 K and around 1723 cm⁻¹ at temperatures below 423 K. The change in wavenumber of the Rh-NO^{δ-} from 1723 cm⁻¹ to 1740 cm⁻¹ appears to be a function of temperature where one form of Rh-NO^{δ-} converts to another

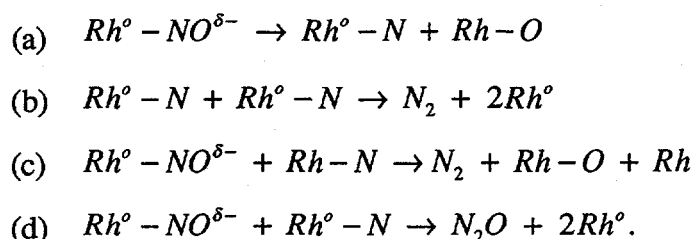
with an increase in temperature. Clear distinction between these two bands is not possible; the difference in structure between the species contributing these two bands cannot be determined.

Assignment of the structure of adsorbed NO on the surface of Rh single crystal and supported Rh catalysts has been based on the presumed analogy in vibrational frequency between adsorbed NO on the metal surface and nitrosyl metal complex. Table 1 summarizes the similarities and the differences in vibrational frequencies of adsorbed NO on the surface of Rh/SiO₂, Rh/Al₂O₃, and rhodium single crystal. The mode of adsorbed NO on Rh catalysts at room temperature has been found to strongly depend on the type of support and Rh dispersion. NO adsorption produced Rh-NO^{δ+} at 1920 cm⁻¹, neutral NO at 1838 cm⁻¹, gem-dinitrosyl NO at 1860 and 1780 cm⁻¹, and Rh-NO^{δ-} at 1740 and 1660 cm⁻¹ on 5 wt% Rh/Al₂O₃ [12] and Rh-NO^{δ+} at 1921 cm⁻¹ and Rh-NO^{δ-} at 1746 and 1656 cm⁻¹ on 4 wt% Rh/SiO₂ [9]. It should be noted that the whole Rh-NO^{δ-} entity should be considered to be neutral. δ- represents the partial charge resulting from the transfer of electron from Rh to NO. The difference in the wavenumber for Rh-NO^{δ-} at 1746 and 1656 cm⁻¹ has been attributed to the different extent of electron back donation from the reduced Rh site to adsorbed NO. The bonding between Rh and NO^{δ-} at 1656 cm⁻¹ (i.e., the low wavenumber Rh-NO^{δ-}) is presumably stronger than that for Rh and NO^{δ-} at 1746 cm⁻¹ (the high wavenumber Rh-NO^{δ-}).

Our recent TPR and transient studies have revealed that the high wavenumber Rh-NO^{δ-} at 1746 cm⁻¹ is less stable than the low wavenumber Rh-NO^{δ-} at 1656 cm⁻¹ [17]; the low wavenumber NO^{δ-} participated in NO dissociation during NO-CO reaction on 4 wt% Rh/SiO₂ with the average Rh crystallite size of 63 Å at temperatures above 473 K [10]. The presence of both low and high wavenumber Rh-NO^{δ-} on the 4 wt% Rh/SiO₂ and the absence of the low wavenumber NO^{δ-} on 0.5 wt% Rh/SiO₂ suggests that the low wavenumber Rh-NO^{δ-} is chemisorbed on the surface of large Rh crystallites. The high wavenumber Rh-NO^{δ-} appeared to be chemisorbed on the surface of highly dispersed Rh on 0.5 wt% Rh/SiO₂. A high dispersion of Rh on 0.5 wt% Rh/SiO₂ is also evidenced by the fact that 0.5 wt% Rh/SiO₂ chemisorbed primarily linear CO as shown in Figure 3.

EELS (Electron Energy Loss Spectroscopy) studies have shown that the surface of Rh(111) single crystal chemisorbs the low wavenumber Rh-NO δ^- at 1620-1644 cm $^{-1}$ and 1510-1570 cm $^{-1}$ which have been assigned to a bent terminal NO and a bridged NO, respectively [15,16]. The low wavenumber (1620-1644 cm $^{-1}$) Rh-NO δ^- observed on both Rh single crystal and supported Rh is in a bent form, exhibiting a Rh-N-O angle of 120 $^\circ$ [18]. Both Rh-NO δ^+ and Rh-NO on Rh/Al $_2$ O $_3$ and Rh/SiO $_2$ are in a linear form which is perpendicular to the Rh surface. Rh-NO δ^+ has only been observed on the supported Rh while bridged NO has only been found on the single crystal surface. The formation of Rh-NO δ^+ on Rh/SiO $_2$ and Rh/Al $_2$ O $_3$ is a result of either oxidation of the Rh surface by dissociative adsorption of NO or direct adsorption of NO on Rh $^+$ sites. The resistance of the Rh single crystal surface to oxidation during dissociative NO adsorption inhibits the formation of Rh $^+$ sites that chemisorb NO δ^+ and gem-dicarbonyl.

The variation in the integrated intensity of the high wavenumber Rh-NO δ^- at 1723-1740 cm $^{-1}$ as a function of temperature is shown in Figure 2(a); the variation in the composition of IR cell effluent is shown in Figure 2(b). The rapid decrease in IR intensity of Rh-NO δ^- in the 343-393 K temperature range corresponds to the desorption of adsorbed NO as gaseous NO and initial formation of N $_2$ and N $_2$ O, suggesting the high wavenumber Rh-NO δ^- is responsible for the formation of N $_2$ and N $_2$ O. Nevertheless, the extensive overlapping between 1723 and 1740 cm $^{-1}$ does not allow determination of their contribution to the product formation. The first N $_2$ peak centered at 427 K correspond to 0.69 μ mole of N $_2$; the N $_2$ O peak centered at 418 K correspond to 0.0053 μ mol of N $_2$ O. The following reaction steps have been suggested to explain the formation of N $_2$ and N $_2$ O products.



Steps (a) and (d) leading to N $_2$ O formation have been supported by ample evidence. Our recent pulse infrared study has shown that the low wavenumber Rh-NO δ^- in step (a) dissociates on

the reduced Rh surface and the formation of N₂O takes place on the reduced Rh sites [10]. Figure 1 also shows that a significant amount of N₂O was produced when the reduced Rh catalyst was exposed to NO. The formation of N₂O from adsorbed NO via steps (a) and (d) should leave an adsorbed oxygen which may modify the Rh surface. On 4 wt% Rh/SiO₂ and 5 wt% Rh/Al₂O₃ dissociative adsorption of NO, step (a), produced Rh⁺ that chemisorbed NO as Rh-NO^{δ+}. The absence of Rh-NO^{δ+} during NO adsorption and TPD indicates that Rh on 0.5 wt% Rh/SiO₂ is not oxidized.

It should be noted that the low wavenumber Rh-NO^{δ-} is not present during TPD. Formation of N₂O and N₂ during TPD should be attributed to dissociation of high wavenumber Rh-NO^{δ-}, $Rh^{\circ} - NO^{\delta-} \rightarrow Rh - N + Rh - O$. Adsorbed N and NO may follow steps (b) and (c) to produce a high temperature N₂ peak at 595 K and a low temperature N₂ peak at 427 K, respectively. Step (c) is supported by the presence of adsorbed NO during the formation of N₂ at 427 K. The slightly lower peak temperature for N₂O than for N₂ at 427 K indicates that step (d) takes place at a slightly lower temperature than step (c). Dissociation of the high wavenumber Rh-NO^{δ-} is not a common rate-determining step for the formation of N₂ and N₂O. Simulation of TPD profiles for adsorbed NO have revealed that both steps (c) and (d) have the same activation energy on a 5 % Rh/SiO₂ [19]. The factors that direct the reaction selectivity toward either (c) or (d) remain to be investigated.

The absence of an O₂ profile in Figure 2 is consistent with the literature in that the oxygen produced from NO decomposition was not readily desorbed below 723 K [15,19,20]. During NO TPD, the O₂ desorption peak occurred at 1,500 K on Rh(111) [15], 1060 K on 5% Rh/SiO₂ catalyst [19], and 1,100 K on Rh filament [20].

The infrared spectra and gaseous composition profile shown in Figures 1 and 2(b) permit the determination of the integrated absorbance coefficient (\bar{A}_{NO}) for Rh-NO^{δ-} by assuming that \bar{A}_{NO} does not vary with the coverage of adsorbed NO and using the relation [21]

$$\bar{A}_{NO} = \frac{1}{C_{NO}} \int_{\nu_1}^{\nu_2} A(\nu) d\nu$$

where \bar{C}_{NO} is the moles of NO chemisorbed per cross sectional area of the catalyst disk, and ν_2 and ν_1 are the upper and lower wavenumber bounds at 1795 and 1460 cm^{-1} , respectively. The amount of NO adsorbed on the 0.5 wt% Rh/SiO₂ catalyst prior to TPD was determined by summing up all the nitrogen containing species obtained from multiplying the area under the TPD profile for each species by its responding factor. The amount of NO adsorbed on 196 mg of the catalyst was calculated to be 154.55 μl , which corresponds to an atomic dispersion based on a conservative estimation. \bar{A}_{NO} for Rh-NO δ^- is determined to be 1.91 $\text{cm}/\mu\text{mol}$.

Figure 3 shows the IR spectra of adsorbed CO on 0.5 % Rh/SiO₂ at 303 K. Pulsing 25 μl of gaseous CO into helium flow did not produce adsorbed CO, indicating that CO adsorption is a slow process. Exposure of the catalyst to gaseous CO in a batch mode produced an intense band for the linear CO at 2049 cm^{-1} , a shoulder band at 2004 cm^{-1} , and bridged CO bands at 1813 and 1761 cm^{-1} at 303 K. The CO species exhibiting these bands are weakly adsorbed on the surface. These species can be easily removed by flowing helium, leaving weak bands at 2030 and 2004 cm^{-1} which may be assigned to Rh(CO)₄ [21].

Figure 4 shows the IR spectra of adsorbates as a function of temperature during the temperature-programmed reaction (TPR) under an NO-CO-He (NO:CO:He=1:1:3) on Rh/SiO₂ catalyst. The initial spectrum prior to the NO-CO TPR shows a Rh-NO band at 1855 cm^{-1} , a Rh-NO δ^- band at 1723 cm^{-1} , and two shoulder bands at 1680 and 1634 cm^{-1} . These shoulder bands are assigned to the low wavenumber Rh-NO δ^- on the reduced Rh. Comparison of initial infrared spectra of adsorbed NO during TPD in Figure 1 and during TPR in Figure 4 shows that the presence of CO in TPR results in the formation of adsorbed NO at 1634 and 1680 cm^{-1} , indicating that CO kept Rh in a reduced state.

Figure 5(a) highlights changes in the IR intensity of adsorbed NO at 1723 cm^{-1} with respect to temperature; Figure 5(b) shows the variation in the composition of the IR cell effluent during TPR. Increasing the temperature from 303 to 453 K led to a gradual decrease in the intensity of adsorbed NO while conversion of reactants to products is negligible, indicating desorption of adsorbed NO. As appreciable conversion of reactants was observed at temperatures

above 475 K where the high wavenumber Rh-NO^{δ-} band shifted to 1740 cm⁻¹. The light-off temperature, at which 50% conversion occurs, was observed at 587 K, where the intensity of adsorbed NO is about 2 % of its initial intensity at 303 K. The light-off temperature under the same reaction condition on 4 wt% Rh/SiO₂ was determined to be 530 K [17]. The major IR-observable products at the light-off temperature are CO₂ and N₂O as shown by their intense IR bands. Because both N₂O and CO₂ give $m/e=44$, the quantitative analysis of these species is not possible with MS without monitoring the secondary ionization of CO₂, $m/e=22$.

Nearly complete conversion of NO was achieved at temperatures above 663 K where the only noticeable adsorbate band was Si-NCO at 2295 cm⁻¹. The Si-NCO band first appeared at 588 K and became prominent at 663K. Si-NCO has been known to be a spectator species for CO₂ formation which remains on the catalyst surface under flowing helium at temperature between 463-723 K [10,22]. The absence of adsorbed NO and CO at temperatures above 618 K indicates that the concentration of these adsorbates is too small to be detected by IR.

In order to observe adsorbed CO during TPR, the ratio of NO to CO was adjusted to 1:10 to increase the concentration of adsorbed CO. Figure 6 shows the IR spectra of the adsorbates; Figure 7 exhibits the composition profile of the IR cell effluent as a function of temperature during TPR with NO:CO:He=1:10:6. N₂O and CO₂ bands emerged at 378 K. Formation of N₂O and CO₂ occurred at significantly lower temperatures than those of the TPR study with NO:CO:He=1:1:3. Figure 7 shows that an appreciable increase in $m/e=44$ starts at 378 K, confirming the formation of N₂O and CO₂. Formation of N₂O from NO-CO reaction has been shown to occur on the reduced Rh surface [10]. The high concentration of CO appears to keep a portion of the Rh in the reduced form, enhancing the formation of N₂O and CO₂. The presence of reduced Rh site is also evidenced by the linear CO band at 2026 cm⁻¹ which emerged at 468 K.

The light-off of the reaction took place at 635 K where Rh-NCO at 2201 cm⁻¹ and Si-NCO at 2295 cm⁻¹ began to appear. Si-NCO is formed by spillover of isocyanates from the rhodium surface onto the support [10,22]. The high concentration of CO favors the formation of both Rh-NCO and Si-NCO. By varying the partial pressure of CO and NO on 5 % Rh/SiO₂, it was also

found that an increase in the partial pressure of CO led to an increase in the Rh-NCO intensity and a decrease in the Rh-NO δ^- intensity [23].

A comparison of the behavior of adsorbed NO and CO on 0.5 wt% Rh/SiO₂ and 4 wt% Rh/SiO₂ shows that the different dispersion of Rh crystallite leads to distinct difference in chemisorptive and reactivity properties [8-10]. Both linear and bridged CO are weakly bonded to the surface of the highly dispersed Rh, but strongly bonded to the surface of large Rh crystallites. During TPR of NO-CO, the high wavenumber Rh-NO δ^- is the dominant adsorbate on 0.5 wt% Rh/SiO₂ while gem-dicarbonyl and both low and high wavenumber Rh-NO δ^- are present below the light-off temperature and linear CO is the major adsorbate above the light-off temperature on 4 wt% Rh/SiO₂. 4 wt% Rh/SiO₂ shows higher activity for NO-CO reaction with a lower light-off temperature than 0.5 wt% Rh/SiO₂. The high light-off temperature for 0.5 wt% Rh/SiO₂ may be related to its high wavenumber Rh-NO δ^- which has less propensity for dissociation than the low wavenumber Rh-NO δ^- .

CONCLUSIONS

The 0.5 wt% Rh/SiO₂ gives highly dispersed Rh which chemisorbs NO as the high wavenumber Rh-NO δ^- at 1740-1723 cm⁻¹ and chemisorbs CO as linear, bridged, and Rh(CO)₄. The bonding for Rh-NO δ^- is significantly stronger than that for Rh-CO. During TPD of Rh-NO δ^- , adsorbed NO decomposed to N₂ as a major product and N₂O as a minor product. The NO-CO TPR shows that CO reduces a portion of the Rh sites, promoting the formation of N₂O at 378 K. For the TPR, increasing CO partial pressure from NO:CO:He=1:1:3 to NO:CO:He=1:10:6 caused a progressive increase in NO conversion and a significant increase in Rh-NCO and Si-NCO concentration. Results of this study and previous studies on 4 wt% Rh/SiO₂ show that differences in Rh dispersion can lead to significant variation in chemisorptive properties and reactivity of the Rh surface. A systematic understanding of the effect of dispersion on the nature of adsorption sites and reactivity remains to be investigated.

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Table 1 Vibrational frequencies (cm⁻¹) of NO on Rh catalysts.

	Rh-NO ^{δ+}	Rh-NO	Rh $\begin{smallmatrix} \nearrow \text{NO} \\ \searrow \text{NO} \end{smallmatrix}$	Rh-NO ^{δ-}	Rh $\begin{smallmatrix} \nearrow \text{NO} \\ \searrow \text{Rh} \end{smallmatrix}$	Ref.
1.2 wt% Rh/Al ₂ O ₃	1910-1920		1830 _(as) 1740-1744 _(s)			[11]
5.0 wt% Rh/Al ₂ O ₃	1920	1838	1860 _(as) 1780 _(s)	1740 (high) 1660 (low)		[12]
0.5 wt% Rh/SiO ₂		1855		1723-1740 (high) 1634-1680 (low)		This Study
4.0 wt% Rh/SiO ₂	1921			1740-1770 (high) 1650-1700 (low)		[9]
4.6 wt% Rh/SiO ₂		1800		1685 (high) 1630 (low)		[13]
5.0 wt% Rh/SiO ₂	1910	1830		1630-1690		[14]
Rh(111)		1840		1620-1644	1510-1570	[15,16]

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Figure 1. IR spectra of NO adsorption at 303 K and 0.1 MPa followed by temperature-programmed desorption on 0.5 wt% Rh/SiO₂.

Figure 2. (a) Variation of absorbant area (between 1795 and 1460 cm⁻¹) of Rh-NO^{δ-} band with temperature.
(b) MS analysis of the effluents from the reactor for Figure 1. Heating rate = 15 K min⁻¹. He = 30 cm³ min⁻¹.

Figure 3. IR spectra of CO adsorption on 0.5 wt% Rh/SiO₂ at 303 K.

Figure 4. IR spectra during the temperature-programmed reaction of NO-CO-He (1:1:3) on Rh/SiO₂. Heating rate = 15 K min⁻¹. He = 30 cm³ min⁻¹.

Figure 5. (a) Variation of absorbant area (between 1795 and 1460 cm⁻¹) of Rh-NO^{δ-} band with temperature.
(b) MS analysis of the effluents from the reactor for Figure 4.

Figure 6. IR spectra during the temperature-programmed reaction of NO-CO-He (1:10:6) on Rh/SiO₂. Heating rate = 15 K min⁻¹. He = 30 cm³ min⁻¹.

Figure 7. MS analysis of the effluents from the reactor for Figure 6.

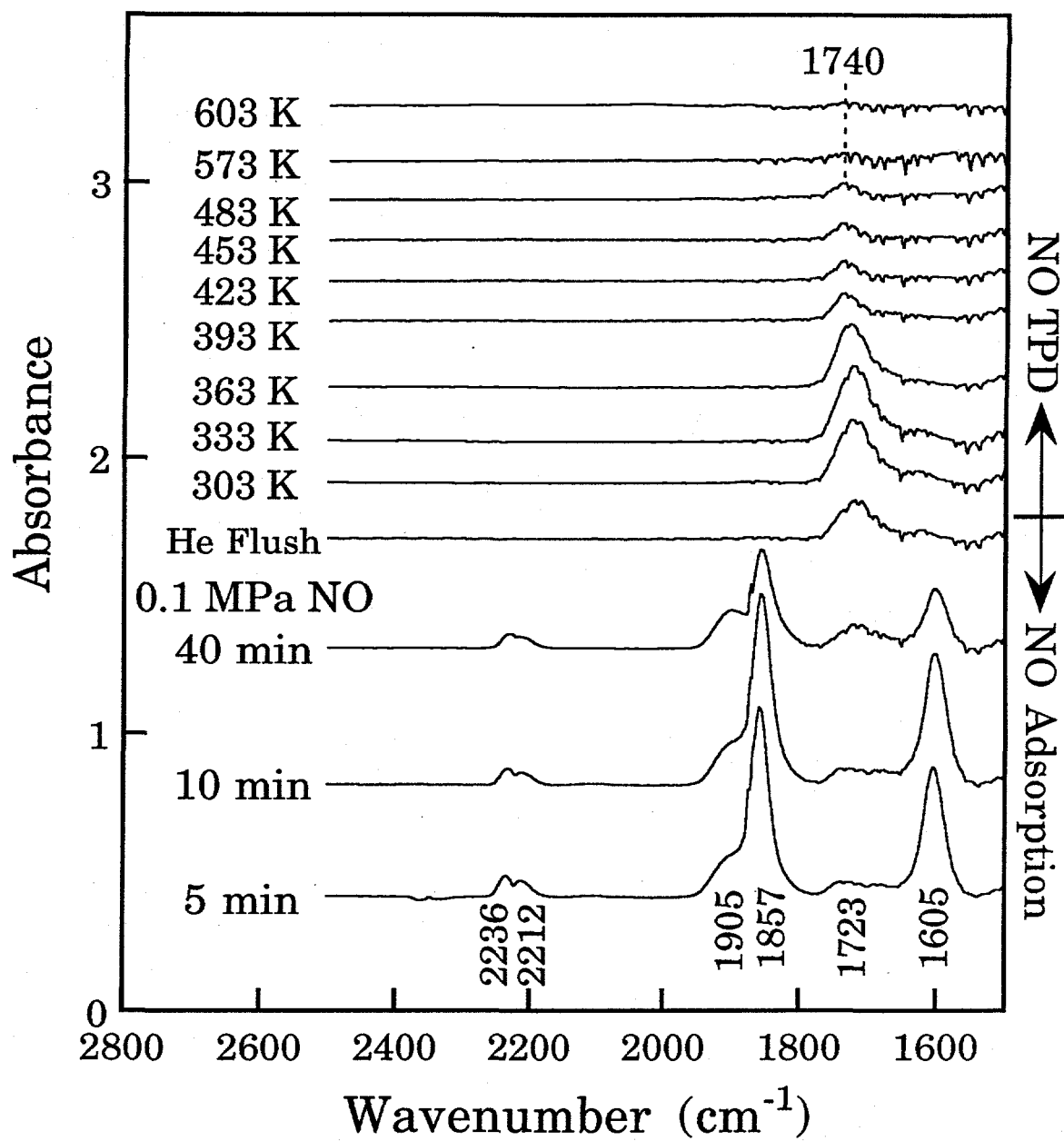


Fig. 1
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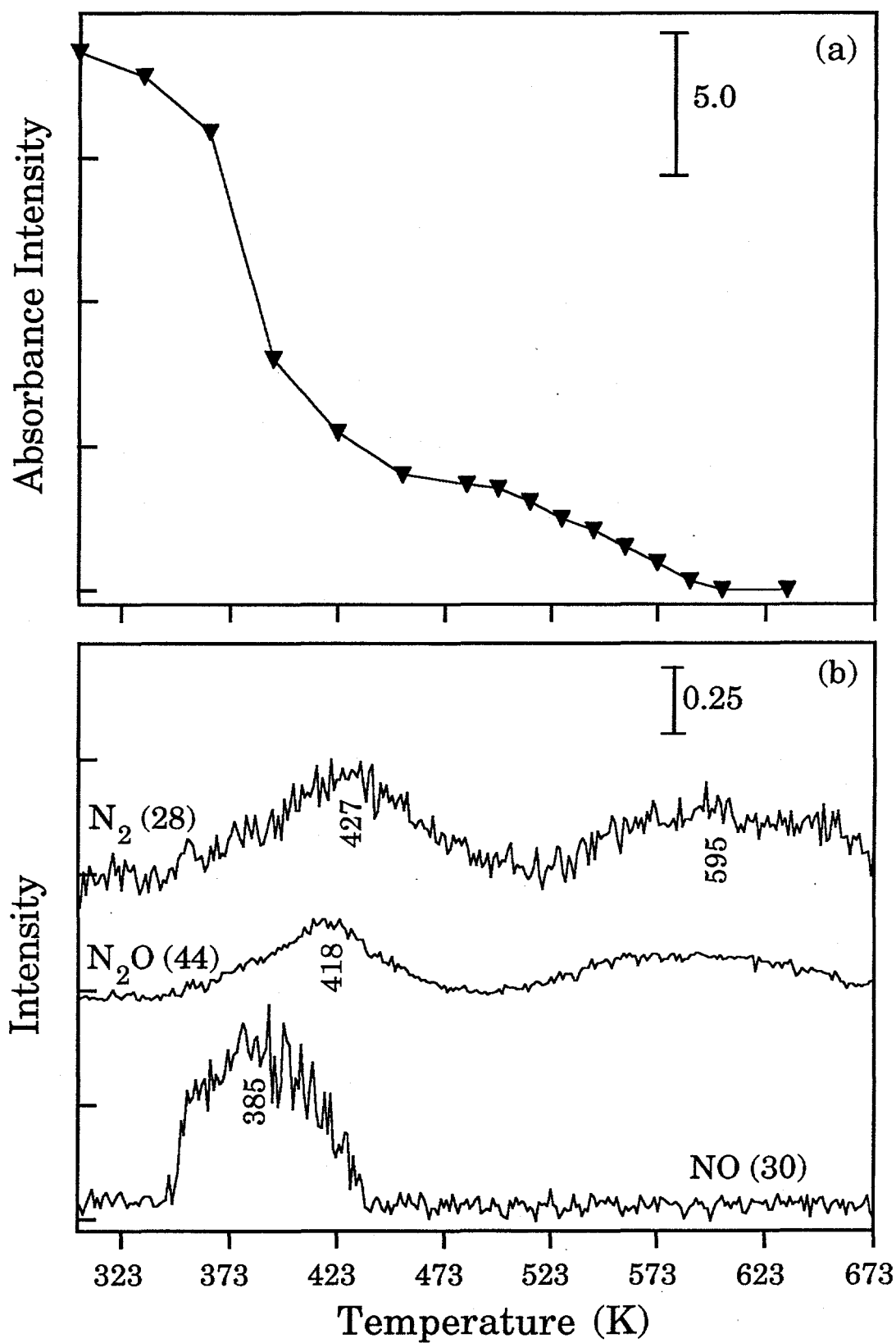


Fig. 2
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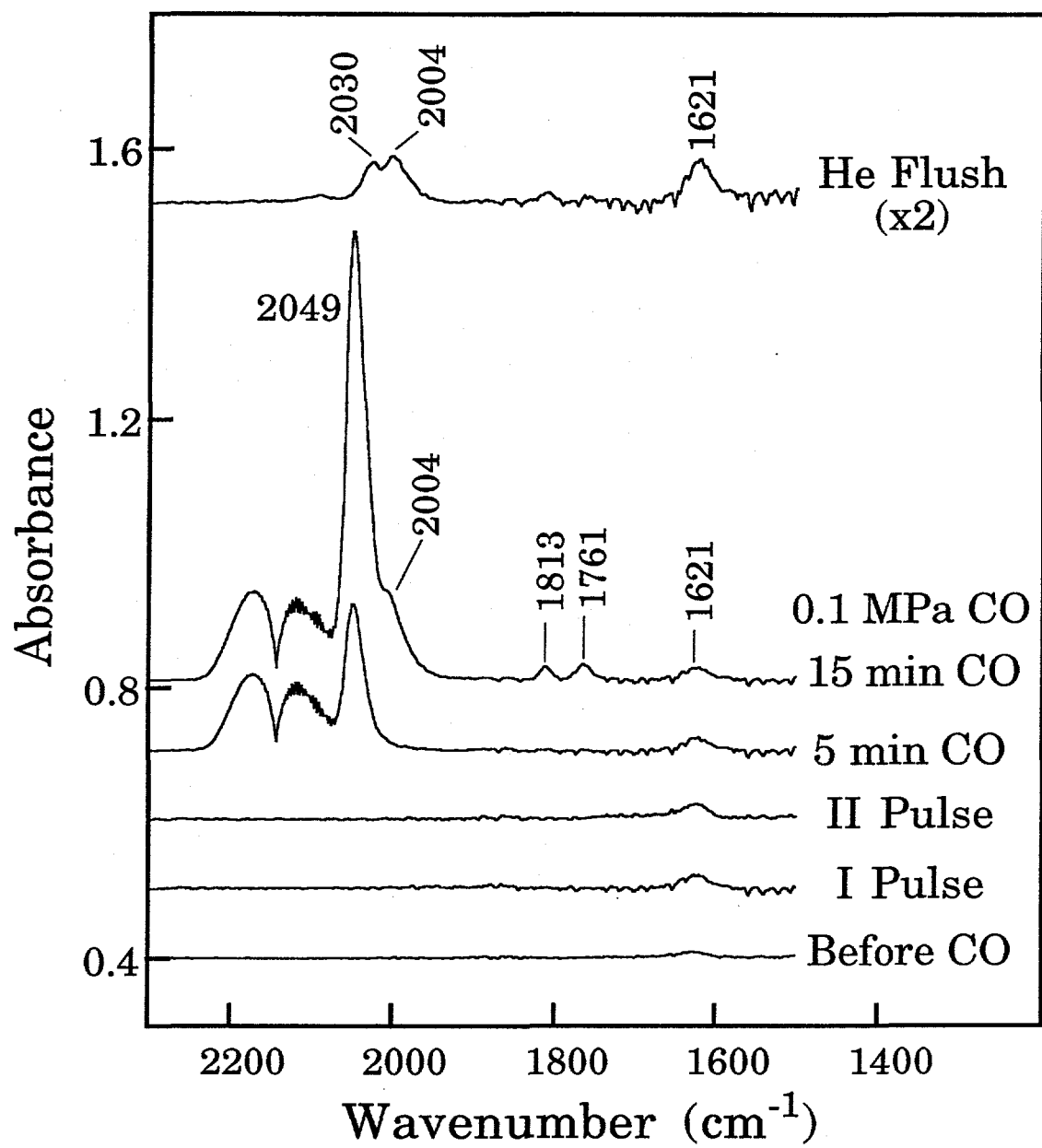


Fig. 3
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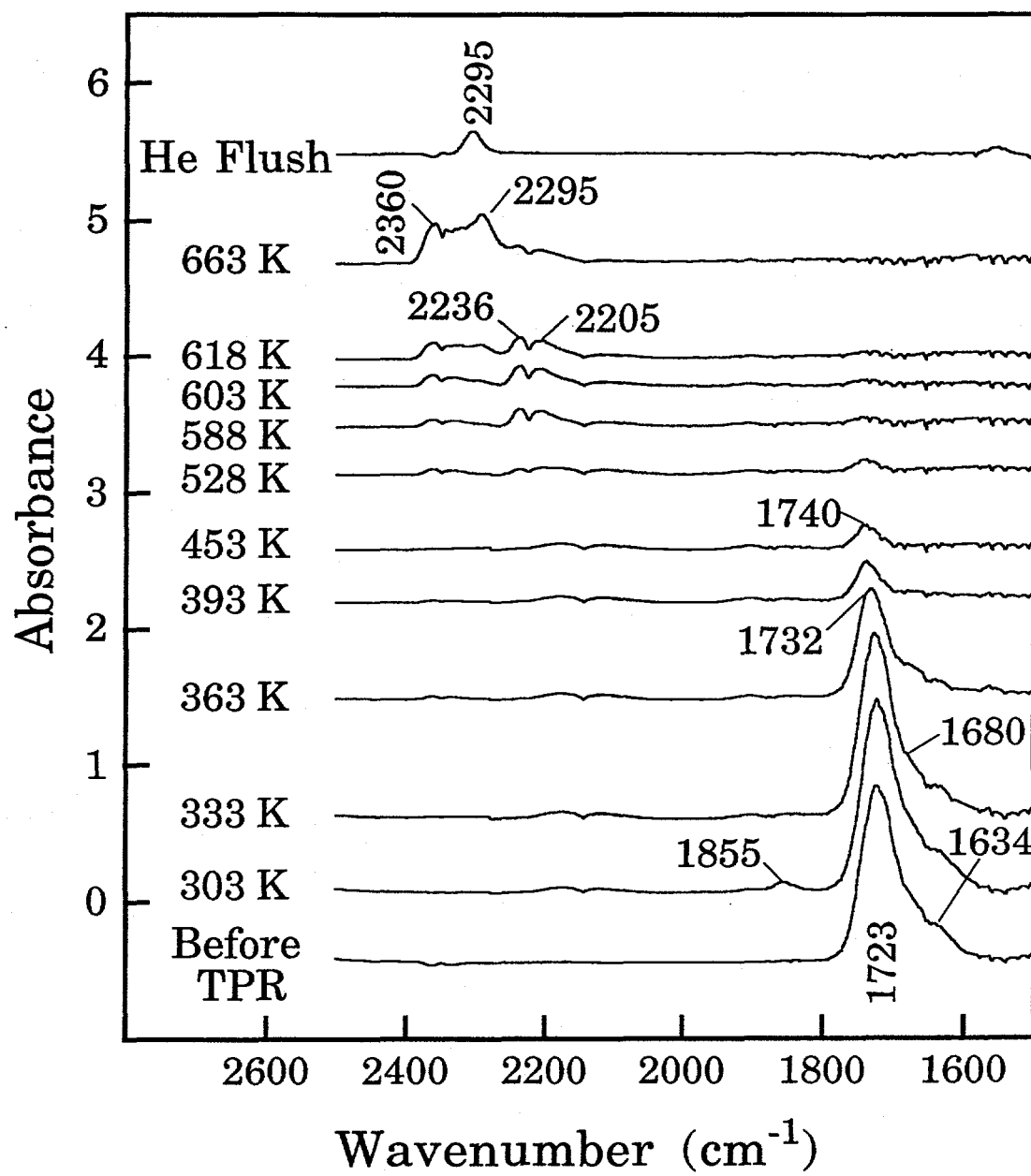


Fig. 4
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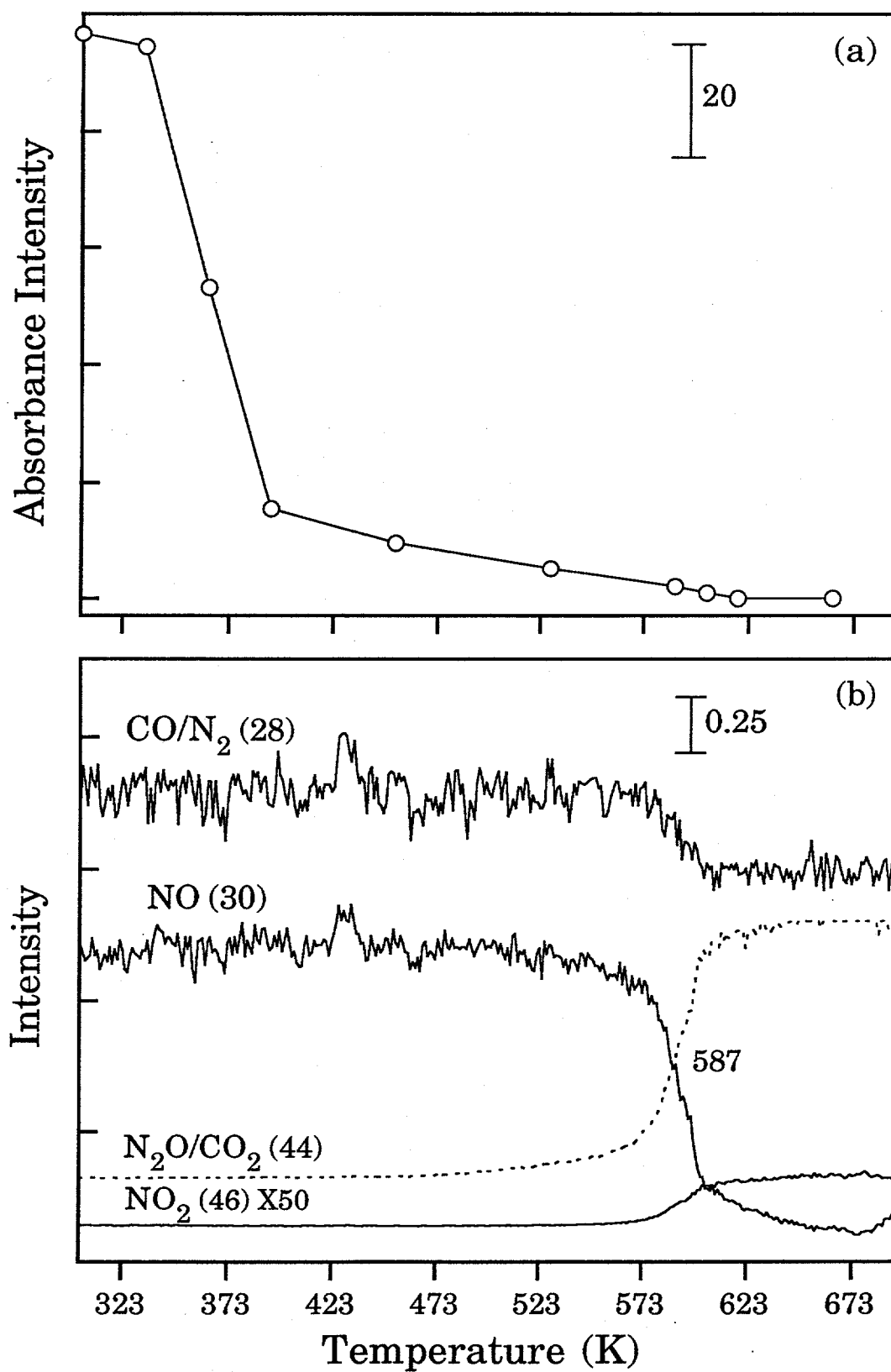


Fig. 5
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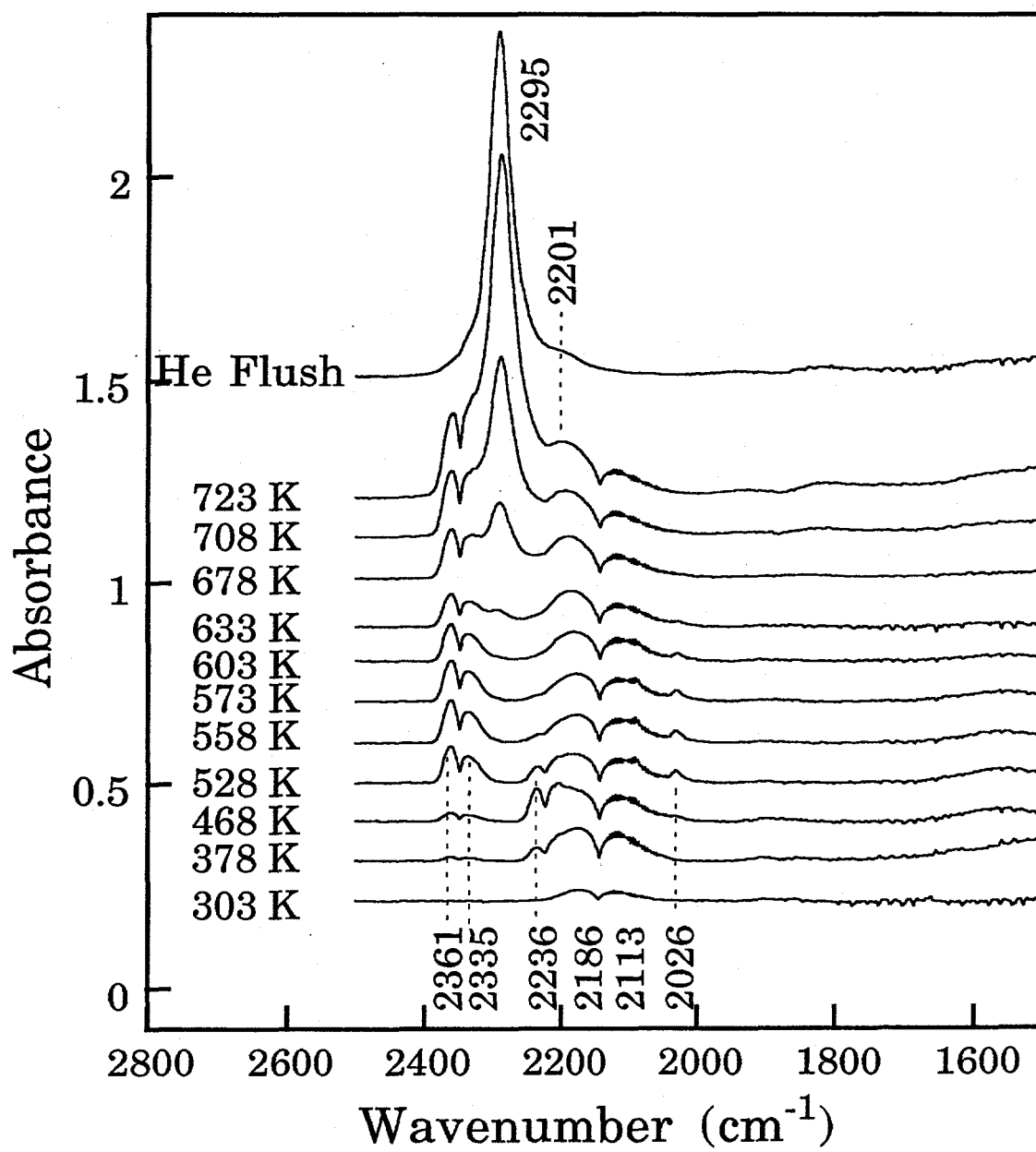


Fig. 6
Chuang et. al.

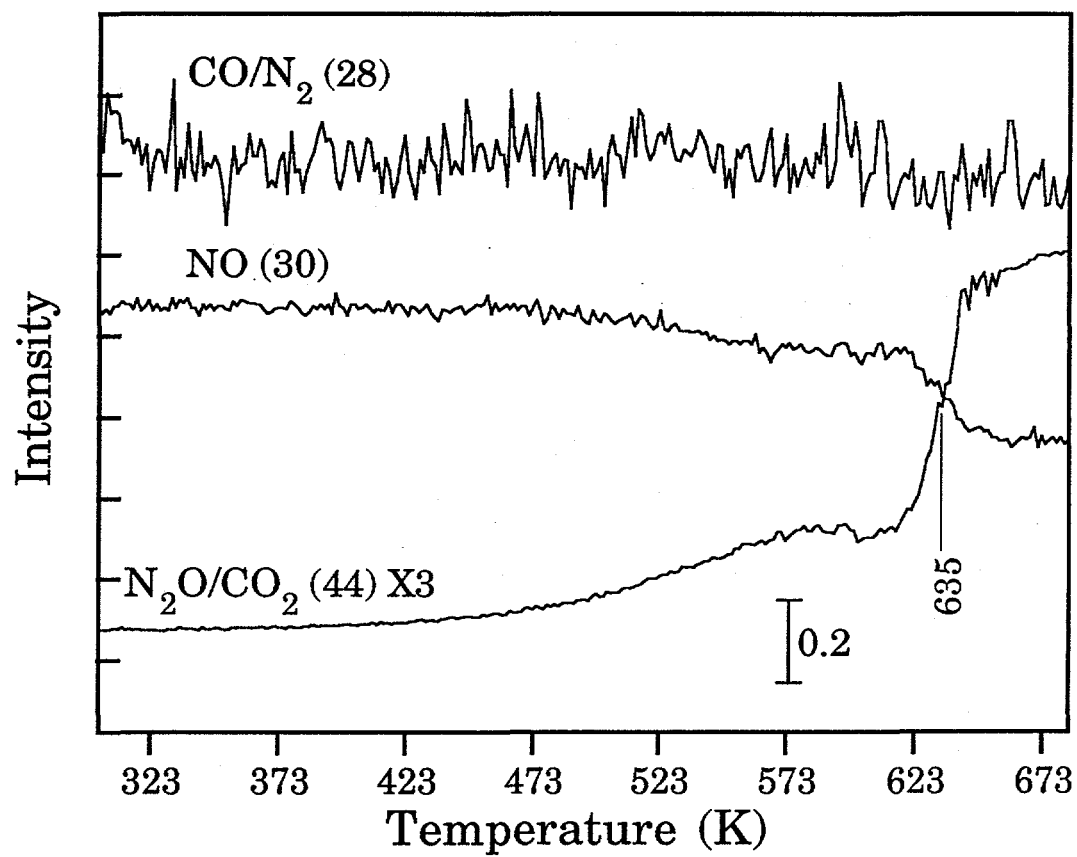


Fig. 7
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